ABSTRACT OF THE DISCLOSURE

There is provided a method for producing an electron source, capable of executing the deposition process within a short time and without limitation in the wave form of the applied voltage.

In producing the electron source in which plural electron emission devices are connected in a matrix by plural row wirings and plural column wirings, the row wirings of a number m (= a × b × c) are divided into groups G_1 to G_a of a number a, and the row wirings in each group are divided into sub groups SG_1 to SG_b of a number b, each containing the row wirings of a number c. The deposition process is executed by voltage application by selecting the row wirings of SG_1 in succession and commonly to all the groups, and such deposition process is thereafter similarly executed on the sub groups starting from SG_2, whereby the deposition process for all the elements is executed by executing the deposition process for each sub group by b times.